

Attorney Docket No.: 99CON114P

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Liu, et al.

Serial No.: 09/575,055

Filed: May 19, 2000

For: Method for Selective Fabrication of
High Capacitance Density Areas in a
Low Dielectric Constant Material

Art Unit: 2818

Examiner: Luu, Chuong A.

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RESPONSE TO FINAL OFFICE ACTION

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Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

OK, to be entered
CML

Dear Sir/Madam:

This is in response to the *Final Office Action* dated July 26, 2005 in the above-referenced patent application. Please enter and consider the following remarks.